

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	381	("mems" or micro adj electro adj mechanical adj system) and 257/414-415.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2006/08/23 12:31
L2	0	(substrate and cotrol adj electrode and driving adj circuit and sensor adj electrode or sensor adj circuit and memory or processor and mirror and control adj electrode).ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2006/08/23 12:20
L3	334	(substrate and cotrol adj electrode and driving adj circuit and sensor adj electrode or sensor adj circuit and memory or processor and mirror and control adj electrode).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2006/08/23 12:20
L4	2	(substrate and control adj electrode and driving adj circuit and sensor adj electrode and sensor adj circuit and memory and processor and mirror and control adj electrode).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2006/08/23 12:20
L5	43	("mems" or micro adj electro adj mechanical adj system) and 257/431-432.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2006/08/23 12:35
L6	6	("mems" or micro adj electro adj mechanical adj system) and 257/444.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2006/08/23 12:35